

<b>INFORMATION DISCLOSURE CITATION</b> <i>(Use several sheets if necessary)</i>		Docket Number (Optional) <b>FIS920010139 (14569)</b>		Application Number <b>Unassigned</b>
		Applicant(s) <b>Casimer M. DeCusatis, et al.</b>		
		Filing Date <b>Herewith</b>	Group Art Unit <b>Unassigned</b>	
*EXAMINER INITIAL <i>HP</i>	OTHER DOCUMENTS <i>(Including Author, Title, Date, Pertinent Pages, Etc.)</i>			
<i>HP</i>	Bann, R., et al., "Micromachining system accommodates large wafers," Laser Focus World, www.optoelectronics-world.com, pp. 189-192, January 2001			
<i>HP</i>	Kartalopoulos, S., "INTRODUCTION TO DWDM TECHNOLOGY Data in a Rainbow," IEEE, Chapter 3, pp. 67-68, (1999)			
<i>HP</i>	Kartalopoulos, S., "OTHER OPTICAL COMPONENTS," IEEE, Chapter 9, pp. 131-137, (1999)			
<i>HP</i>	Carroll, J., et al., "Distributed feedback semiconductor lasers," IEE Circuits, Devices and Systems Series 10, SPIE Press Monograph, Vol. PMS2, pp 9-15, (1998)			
EXAMINER <i>Naughan</i>	DATE CONSIDERED <i>05/14/04</i>			

\*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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